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2000

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re application of:

K. Hashimoto et al.

Application No.: 10/028,429

Filed: December 28, 2001

Group Art Unit: 2823

Examiner: K. Nguyen

Docket No.: 107317-00039

For: DRY ETCHING WITH REDUCED DAMAGE TO MOS DEVICE

AMENDMENT UNDER 37 C.F.R. § 1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 16, 2003

Sir:

INTRODUCTORY COMMENTS

In reply to the Office Action mailed June 16, 2003, please consider the following remarks:

Please enter the Amendment
K.N.
10/02/03